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					FILING DATE Filed herewith		GROUP		
U.S. PATENT DOCUMENTS									
*Examiner Initial		Document Number	Date	Name		Class S	Subclass Filing Date If Appropriate		
M.	AA	6,187,679	2/13/01	Cabral, Jr. Et al.					
XH.	AB	6,362,086	3/26/02	Weimer et al.					
BH.	AC	5,852,319	12/22/98	Kim et al.					
ÖУ.	AD	5,997,634	12/1/99	Sandhu et al.					
<i>3</i> 4.	AE	6,090,708	7/18/00	Sandhu et al.					
34	AF	6,306,766	10/23/01	Sandhu et al.					
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				FOREIGN PATENT DOCUMENTS		/			
		Document Number	Date	Country		Ciass S	Subclass Trainlation Yes No	_	
	AK							Z	
	OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)								
	AM "Mechanisms for enhanced C54-TiSi; formation in Ti-Ta alloy films on single-crystal Si*. A. Quintero et al.; Journal of								
134.			Materials Research; Vol. 14, No. 12 Dec. 1999 pp. 4690-4700						
7				·					
O.Y.s.	AN *Enhanced formation of the C34 TiSi, by an interposed layer of molybdenum"; A. Mouroux et al.; Appl. Phys. Lett. 69 12 August 1996; ©1996 American Institute of Physics								
4,,	AO *Law temperature formation of C54-TiSi, using titanium alloys*, C. Cabral, Jr. Et al; Appl./ Phys. Lett. 71 (24) 15 December 1997 ©1997 American Institute of Physics; pp. 3531-3533								
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	AP								
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EXAMINED Symme A. Surley DATE CONSIDERED 9/18/04									
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